

WHAT IS CLAIMED IS:

1. A method for the production of a support for a lithographic printing plate precursor that comprises providing on a grained aluminum support having an anodic oxide film formed thereon a layer of inorganic compound particles having a major axis larger than a pore diameter of the anodic oxide film and treating the layer of inorganic compound particles with a treating solution capable of dissolving the inorganic compound particles, thereby fusing together the inorganic compound particles to form a layer of the inorganic compound.
2. The method for the production of a support for a lithographic printing plate precursor as claimed in Claim 1, wherein the treating solution comprises a compound containing at least one of fluorine and silicon.
3. A support for a lithographic printing plate precursor that comprises a grained aluminum support having an anodic oxide film formed thereon and a layer of inorganic compound provided on the anodic oxide film, wherein a ratio of pore diameter of the layer of inorganic compound to pore diameter of the anodic oxide film is not less than 1.5 and a ratio of fluorine concentration or a ratio of silicon concentration of the layer of inorganic compound to the anodic oxide film is not less than 2.